

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : Volker BECKER et al.
International Application No. : PCT/DE00/01836
International Filing Date : 06 June 2000
U.S. Serial No. : 10/031,842
For : **DEVICE AND METHOD FOR ETCHING A
SUBSTRATE BY USING AN INDUCTIVELY
COUPLED PLASMA**
Confirmation No. : 8531

Commissioner for Patents
Box PCT
Washington, D.C. 20231

Attention: DO/EO/US

**RESPONSE TO MISSING REQUIREMENTS
UNDER 35 U.S.C. 371**

S I R :

In response to the Notification of Missing Requirements Under 35 U.S.C. 371 in the United States Designated/Elected Office (DO/EO/US) (mailed April 10, 2002), Applicants submit herewith a fully executed Declaration, in order to complete the filing requirements for the U.S. national phase of the above-identified PCT application. The application filed in the Patent Office is the application which the inventors executed by signing the Declaration and Power of Attorney. A copy of the Notification of Missing Requirements is enclosed.

The Office is authorized to charge the \$130.00 fee to cover the surcharge for late filing of the Declaration and any additional fees to Deposit Account No. 11-0600.

06/13/2002 SNAJARRO 00000106 110600 10031842
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Date:

6/10/02

Respectfully submitted,

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